

ABSTRACT OF THE DISCLOSURE

A column for purifying gases by a dry method contains a horizontal plate fitted at a position above a bed of a purifying agent and below a gas inlet, and an upstanding pipe passing through the center of the horizontal plate for guiding harmful gases from the gas inlet to below the horizontal plate, and inner wall surface of the column, upper surface of the horizontal plate and outer wall surface of the pipe form a space defining a collector for the powdered material. Thus there is provided a purifying means which facilitates the purification of harmful gases discharged from e.g. a semiconductor manufacturing process and containing powdered material without accompanying blocking of a purification apparatus, and, thereby, make the operation for the purification and maintenance of the facilities easy, while allowing a purifying agent to exhibit its purifying ability thoroughly.